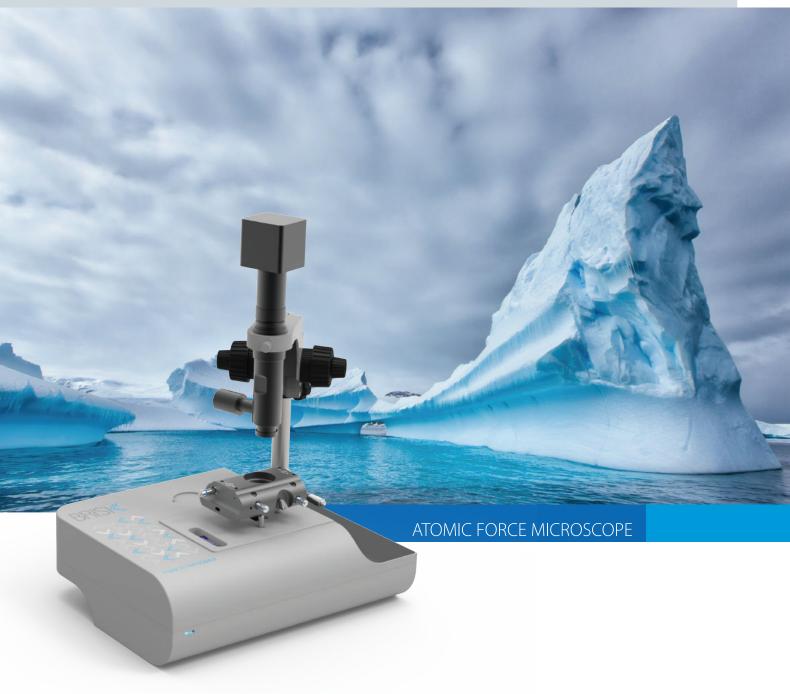


Inspects NanoSpace





Inability of optical microscopes in imaging sizes smaller than wavelength of visible light resulted in invention of nanoscopes in the last decades. AFM is the top in the list due to its low price and multi-applications.

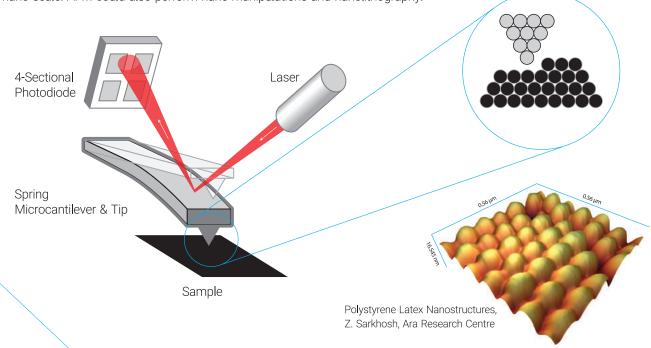
The basic principle of AFM

A spring micron size cantilever has a conical tip at its free end. The conical tip with a very sharp end, usually less than 10 nanometres, scans the sample surface from a very close nanometric distance.

As the tip moves over the surface the Van Der Waals forces between atoms on the sharp end of the tip and atoms on the surface of the sample varies, resulting vertical displacements of the cantilever.

Vertical movements of the cantilever are sensed by an optical method. The reflected laser beam from the cantilever backside hits a quadruple photodiode. The output signals of the photodiodes are related to the vertical movements of the cantilever which in turn represents the surface topography of the sample.

Nowadays AFM is the main tool in Nano research works. Apart from 3-dimensional nanoimaging, AFM is capable of determining various properties of the sample in nano scale. AFM could also perform nano-manipulations and nanolithography.



Our valuable experience in equipping over 80 universities and research centres to AFMs and our view to extend our market to all continents directed us to a new design on the technology edge.

- » Elegant and innovative appearance, modest volume.
- >>> Extremely user friendly; eliminating strains on users.
- » Nano imaging in least possible time duration.
- >> Robustness









The above features, plus using the latest technologies in manufacturing BRISK, has produced an splendid apparatus for nano researchers. with 20 years of experience in producing nano technology equipment, today is setting forth the sophisticated functioning modes of AFM in an spectacular product.

Quality control of high-tech products



Solar cells, semiconductors and integrated circuits

Surface engineering material science



Ceramics and coatings

Polymers and chemical products



Nano-scale mechanical and electrical properties



Biotechnology research











ATOMIC FORCE MICROSCOPE









- Simplified procedure for nano-imaging Simplifications in operation together with reducing the required time for nano-imaging has made Brisk extremely user friendly.
- Developed tip fixing procedure You can calmly fix the tip in AFM-head in the shortest possible time.
- High magnification OM
 The initial imaging for choosing the scan point is performed using a powerful OM fixed on the machine.
- Adopted with all computer types PCs, laptops, all-in-one or any other computer types can be used with Brisk.

- New generation of the controller Employing the latest advanced electronics in Brisk has improved the controller functioning.
- LAN feature
 One single network cable does all data transfer between computer and the machine.
- Fast Approach Saving time during approach by using fast approach technique is a marvellous feature of Brisk.
- Fantastic design, compact
 Brisk occupies least possible space in your laboratory and its nice looking view attracts the users.









Direct online communication

Network possibility provides simultaneous connection of technical specialist and the user to Brisk. This feature speeds up user's problem solving and troubleshooting. Further, one may operate Brisk from any station in network and no need to be present in the lab.



Developed software

Highly-magnified tip and sample view, obtaining & auto-saving nano images and signals monitoring are unique features of the latest version of Brisk software.



Straight and easy tip-fixation

Thanks to the new head design, providing the easiest way of fixing the tip without usual user's stress. Picking and putting of the tip is performed with the least possible risk of breakage.



Time saving in approach

Swift commence of scanning is due to sophisticated fast approach technique implemented in Brisk.

SPECIFICATIONS

Scanner

XY Scanner

50 µm Maximum XY scan range

1 nm XY resolution

Z Scanner

4 µm Maximum Z scan range

0.1 nm Z resolution

Electronics

ADC and DAC Channels

4 Channel ADC 24bit

4 Channel DAC 24bit

Signal processing

40 MHz Frequency zyng processor

Integrated functions

100 MB/sec Via LAN

Stage

XY Stage

Motorized software-controlled

15 mm Travel range

40 nm Movement steps

Z Stage

15 mm Travel range

40 nm Movement steps

Automatic engage of the cantilever to the sample surface (Auto Fast Approach)

Sample Mount

20 mm Maximum sample diameter

10 mm Maximum sample thickness

Includes light magnetic sample holder

-10 V to +10 V Bias voltage range to the sample

Software

Data acquisition

Real-time 100 MB/sec Microsoft Windows compatible Integrated optical view windows for sample and cantilever vision

Monitoring all system signals with a high rated oscilloscope

Auto saving captured images in software gallery Scanning zoom-selected area on captured images Automatic fast approach of cantilever to the sample surface (Auto Fast Approach)

Image processing

Independent software for image processing, data analysis and presentation

Capability of exporting different data of images Built-in with all Microsoft OS

Top Veiw Optical Microscope

8-Megapixel resolution, color

60X to 600X Optical zoom

Integrated lighting

Include microscope dimmer

Dedicated Computer Configuration

21.5" Display Monitor

Core i5-7200U CPU

8GB DDR4 RAM

2GB GeForce Graphic, 1920*1080 Resolution

Head

High precision adjustment micrometer

670 nm Laser frequency

5 mW Maximum laser diod power

High grade quadruple photo-diode

Dithering mechanism

Optimized optical path design

Spring lever tip holder mechanism

AFM Unit

Plug and Play

Dimension

300 mm × 400 mm × 300 mm

Net Weight

20 Kg

Options/Accessories

Standard test samples, sample mounting kit, sample substrate

Various types of cantilevers

Tip changing kit including vacuum pen, tweezers, magnet box, head holder unit

Functional Modes

Standard Version Modes: Contact, Non-Contact, Tapping, Phase image, Lateral Force Microscopy (LFM) Advanced Version Modes: Magnetic Force Microscopy (MFM), Electric Force Microscopy (EFM), Force Spectroscopy + All Standard Modes

Full Version Modes: Chemical and Mechanical Nano-Lithography, Force Modulation Microscopy (FMM) + All Advanced Modes

Full Plus Version Modes: Kelvin Probe Force Microscopy (KPFM), Conductive AFM (C-AFM), Piezoresponce Force Microscopy (PFM), Frequency Modulation (FM) + All Full Modes

